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Docket No.: 9323.050.00-US  
(PATENT)

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Patent Application of:

In-Kwon Jeong

Confirmation No.: 1220

Application No.: 09/917,344

Group Art Unit: 1763

Filed: July 27, 2001

Examiner: Macarthur, S.

For: CMP SYSTEM AND METHOD FOR  
EFFICIENTLY PROCESSING  
SEMICONDUCTOR WAFERS

Customer No.: 30827

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MAY 13 2004

**OFFICE OF PETITIONS**

**AMENDMENT IN RESPONSE TO NON-FINAL OFFICE ACTION**

Commissioner for Patents  
Alexandria, VA 22313-1450

Dear Sir:

In response to the Office Action dated June 2, 2003, please amend the above-identified U.S. Patent application as follows:

**Amendments to the Claims** are reflected in the listing of claims which begins on page 2 of this paper.

**Remarks** begin on page 15 of this paper.